

PRODUCT TECHNICAL BRIEF

2L-200C Sputter-Ion Pump, 220 L/s

2L-200C Sputter-Ion Pump, 220 L/s - LeakLab solutions for leak testing, vacuum systems and test equipment.

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Technical Data

PARAMETER	PUBLISHED VALUE / INFORMATION
Nitrogen pumping speed	220 L/s
Argon pumping speed stated in source record	Approximately 24 L/s
Ultimate pressure	$\leq 1 \times 10^{-8}$ Pa
Maximum start pressure	$\leq 5 \times 10^{-4}$ Pa
Inlet flange	CF150
Maximum bakeout temperature	<200 °C with magnets / <300 °C without magnets
Bakeout jacket	Included in the source configuration
High-voltage power supply	Included in the source configuration
Indicative dimensions	Approximately 500 × 265 × 430 mm

Technical and Project Information

Oil-free 2L-200C diode sputter-ion pump with a stated nitrogen pumping speed of 220 L/s and ultimate pressure of $\leq 1 \times 10^{-8}$ Pa. The source configuration includes a bakeout jacket and high-voltage power supply. Confirm the current datasheet and scope of supply before ordering.

2L-200C Diode Sputter-Ion Pump

The 2L-200C is a medium-size oil-free ion pump for long-cycle vacuum processes, leak-testing stations and analytical systems. It has no rotating parts and therefore adds no mechanical pump vibration or hydrocarbon backstreaming to the vacuum chamber.

Use a short, high-conductance CF connection, an appropriate preliminary vacuum stage and controlled bakeout. Monitor discharge current and follow the manufacturer's regeneration procedure for inert or heavy-gas service.

Confirm the current manufacturer datasheet, gas-specific performance, voltage and polarity, controller, cable, magnets, bakeout hardware and flange before ordering. LeakLab integration and commissioning services are available subject to

an agreed scope.

- Vacuum Pumps Atmosphere-to-High-Vacuum Dry Pumps High-Vacuum Pumping Stations Ion Pumps Diode Ion Pumps for Heavy Gases Triode Ion Pumps for Noble Gases KYKY RV Rotary-Vane Pumps Roots Booster Pumps Screw Vacuum Pumps Tank Evacuation Systems Turbomolecular Pumps
- Atmosphere-to-High-Vacuum Dry Pumps
- High-Vacuum Pumping Stations
- Ion Pumps Diode Ion Pumps for Heavy Gases Triode Ion Pumps for Noble Gases
- Diode Ion Pumps for Heavy Gases
- Triode Ion Pumps for Noble Gases
- KYKY RV Rotary-Vane Pumps
- Roots Booster Pumps
- Screw Vacuum Pumps
- Tank Evacuation Systems
- Turbomolecular Pumps
- Helium Reference Leaks
- Scanning Electron Microscopes
- Leak-Detector Accessories

WORLDWIDE PROJECT CONTACT

Send the test object or system, operating conditions, target sensitivity or pressure range, applicable standard, destination country, quantity and schedule. LeakLab will review the project scope.

mail@leaklab.org

Regarding: 2L-200C Sputter-Ion Pump, 220 L/s

Specifications, standards, verification scope, availability and commercial terms must be confirmed for the exact configuration and destination jurisdiction before order or project acceptance.